

Docket No. 0160-0198 PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, et al.

GAU: 1754

SERIAL NO: 09/463,961

EXAMINER: T. VANOT

FILED: May 25, 2000

FOR: METHOD AND APPARATUS FOR PROCESSING EXHAUST GAS OF SEMICONDUCTOR  
FABRICATION

NOTICE OF APPEAL

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Applicants hereby appeal to the Board of Appeals from the decision dated November 21, 2001

The items checked below are appropriate:

- ☐ A Petition for Extension of Time Under 37 C.F.R. §1.136 was filed for \_\_\_\_\_ months.
- ☐ A timely response to the final rejection has been filed, as provided in 841 O.G. 1411.
- ☒ A Petition for Extension of Time for filing the Notice of Appeal is attached.

Fee: \$320.00

- ☐ Applicant claims small entity status. See 37 CFR 1.27.
- ☒ Is Enclosed
- ☐ Charge to Deposit Account No. 15-0030 (an additional copy of this notice is enclosed herewith).
- ☒ Please charge any additional fees or credit any overpayment of fees required for filing the Notice of Appeal to Deposit Account No. 15-0030. A duplicate copy of this Notice is enclosed.
- ☒ If this notice is not considered timely filed by the U.S. Patent and Trademark Office, then a petition is hereby made under 37 C.F.R. §1.136, and any additional fees required under 37 C.F.R. §1.136 for any necessary extension of time may be charged to Deposit Account No. 15-0030. A duplicate copy of this Notice is enclosed.

RECEIVED  
MAY 23 2002  
TC 1700

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



Norman F. Oblon

Registration No. 24,618

Corwin P. Umbach, Ph.D.

Registration No. 40,211



22850

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 10/01)

05/22/2002 AWONDAF1 00000146 09463961

01 FC:119

320.00 OP